## **PlasmaEtch PE-50 Standard Operating Procedure**



## NYU Tandon School of Engineering Nanofabrication Facility



Figure 1: PlasmaEtch PE-50



Figure 2: PlasmaEtch PE-50 Control Panel

- 1. Startup
  - a. Enable tool in Badger Software. Enabling tool will allow process gases to flow.
- 2. Command Entry (See Fig. 2)
  - a. Press "Enter" key to initialize power
  - b. Press "Enter" key again to go into the commands menu
  - c. Pushing the "left" or "right" arrow key from the "Commands" menu will take you to the "set-up" menu. Press the "Enter" key to access the settings. System timers and other set-up parameters are entered in this area
  - d. Use the "left" and "right" arrow keys to find a menu item within a menu area. Use the "up" arrow key to go to a previous menu area. Use the "enter" key to select a menu item.
- **3. Tool Operation Settings** 
  - a. Plasma Time: 00:00 to 59:59; set time then press "enter"
  - b. Vacuum Set Point: 1.0 to 1000.0 mTorr Vacuum level set point required before gases are introduced into the chamber. Set the value then press "enter"
  - c. Atmospheric Vent: 0-59.59 minutes Time allowed for chamber to vent to atmosphere when "CYCLE STOP" is initiated. Set value then press "enter"
  - d. Purge Vent: 0-59 seconds Time allowed for purge air to be introduced in the chamber at the completion of a cycle. Set value then press "enter"

- e. Gas Stability: 0-59 seconds Delay before RF Power is applied after process gases are on. Set value then press "enter"
- f. Vacuum Alarm: 0-59.59 minutes Amount of time required to pump the system down to vacuum set point before initiating an alarm. Set value, then press "enter"
- 4. Tool Operation
  - a. After the last operation setting has been input, press the "up" key to go to the setup menu
  - b. Press the "left" or "right" key(s) to cycle through the different menus, until "commands" menu is reached
  - c. Press the "Enter" key to access the "Commands" menu.
  - d. Select the "Plasma" command.
  - e. Load the material to be processed. Close the chamber door.
  - f. Run a 15-minute warm up cycle to allow the system to stabilize before processing material.
  - g. Actuate the "Enter" key to start the cycle. The vacuum pump will start, and the chamber vacuum reading will be displayed.
  - h. The vacuum chamber will pump down to set point, process gases will enter the chamber.
- 5. Run process
  - a. The vacuum chamber will pump down to set point, process gases will enter the chamber.
  - b. The process gases entering the chamber will become stabilized

- c. RF power will be applied to the process gases, creating a plasma. The plasma process timer will start. The plasma process indicator will light up to signal that the plasma process is occurring (See Fig. 1)
- 6. Process complete
  - a. Process timer stops, plasma process indicator light turns off
  - b. RF power is turned off
  - c. Plasma glow is extinguished
  - d. Process gas valves are turned off
  - e. Vacuum pump is turned off
  - f. Chamber vent valve is opened for time set in "Purge Timer".
  - g. Chamber is pumped down to vacuum set point in "Vacuum Set" parameter
  - h. After the vacuum set point is reached, the process is complete
  - i. The "Plasma Cycle Complete" message will be displayed in the system status area
  - j. The vacuum chamber will be vented according to the time programmed in the "Atmospheric Vent" timer setting in the set-up menu.
  - k. Remove sample from tool and log off tool from Badger system.